## Resistance and surface potential characterization of 2-d materials with atomic force microcopy

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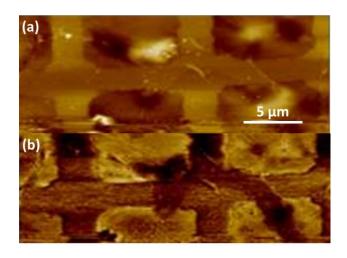
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Over the past 30 years, Atomic Force Microscopy evolved from has microscope to measurejust the surface topography to a wide variety measurement modes that provides a way to characterize other atomic interactions or physical properties like magnetic field, electric nanoscale field, dissipation processes, thermal conductivity, electrical conductivity, resistance, surface potential, piezoresponse, Young modulus,... Electrical nanocharacterization with **AFM** emerged as a powerful tool to map electrical properties at the nanoscale, like surface potential (work function) conductivity. However, traditional setups in AFM make difficult to obtain accurate and repeteable results over several types of samples.

In this contribution we will show the capabilities new developed AFM modes: High Definition Kelvin Force Microscopy (HD-KFM), ResiScope, Soft-Resiscope Scaning Microwave that overcome the intrinsic difficulties of electrical nanocharacterization with AFM. techniques have been applied on a variety of samples of 2-D materials providing high stability, sensitivity and lateral resolution

- [4] 4.T.R. Albrecht, P. Gr"utter, D. Horne, D. Rugar, J. Appl. Phys. 69, 668 (1991).
- [5] 5.T.R.Rodriguez and R.Garcia App. Phys. Lett. 84(3):449-451
- [6] 6. J. Colchero, A. Gil, A.M. Bar'o, Phys. Rev. B 64, 245403 (2001) Authors, Journal, Issue (Year) page

**Figures** 



**Figure 1:** Topography (a) and surface potential (b) of a grafphene membrane suspended over a grid of Si/SiO2.

## References

- [1] 1.G. Binnig, C.F. Quate, Ch. Gerber, Phys. Rev. Lett. 56, 930 (1986).
- [2] 2.Houzé F, Meyer R, Schneegans O, Boyer L.. Appl Phys Lett. 1996;69:1975.
- [3] 3.D.W. Abraham, et al, J. Vac. Sci. Technol. B 9,703 (1991)